

PATENT ASSIGNMENT

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SUBMISSION TYPE:	NEW ASSIGNMENT										
NATURE OF CONVEYANCE:	ASSIGNMENT										
CONVEYING PARTY DATA											
<table border="1"><thead><tr><th>Name</th><th>Execution Date</th></tr></thead><tbody><tr><td>Hamid Balamane</td><td>02/02/2009</td></tr><tr><td>Thomas Dudley Boone Jr.</td><td>02/20/2009</td></tr><tr><td>Jordan Asher Katine</td><td>01/22/2009</td></tr><tr><td>Barry Cushing Stipe</td><td>02/03/2009</td></tr></tbody></table>	Name	Execution Date	Hamid Balamane	02/02/2009	Thomas Dudley Boone Jr.	02/20/2009	Jordan Asher Katine	01/22/2009	Barry Cushing Stipe	02/03/2009	
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RECEIVING PARTY DATA											
Name:	Hitachi Global Storage Technologies Netherlands B.V.										
Street Address:	Locatellikade 1										
Internal Address:	Parnassustoren										
City:	1076 AZ Amsterdam										
State/Country:	NETHERLANDS										
PROPERTY NUMBERS Total: 1											
<table border="1"><thead><tr><th>Property Type</th><th>Number</th></tr></thead><tbody><tr><td>Application Number:</td><td>12345715</td></tr></tbody></table>	Property Type	Number	Application Number:	12345715							
Property Type	Number										
Application Number:	12345715										
CORRESPONDENCE DATA											
Fax Number:	(512)472-9123										
<i>Correspondence will be sent via US Mail when the fax attempt is unsuccessful.</i>											
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ATTORNEY DOCKET NUMBER:	HSJ920080159US1										
NAME OF SUBMITTER:	Michael E. Noe, Jr.										
Total Attachments: 2 source=Assignment#page1.tif											

CH 12345715 \$40.00

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PATENT
REEL: 022369 FRAME: 0291

ASSIGNMENT FOR PATENT APPLICATION

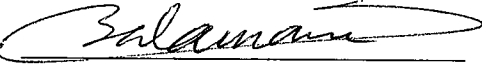
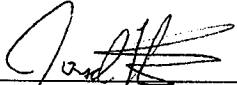
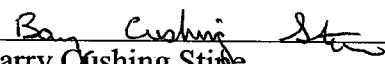
Whereas, I/we the undersigned inventor(s) have invented certain improvements as set forth in the patent application entitled:

SYSTEM, METHOD AND APPARATUS FOR FABRICATING A C-APERTURE OR E-ANTENNA PLASMONIC NEAR FIELD SOURCE FOR THERMAL ASSISTED RECORDING APPLICATIONS

Whereas, **Hitachi Global Storage Technologies Netherlands B.V.**, having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands (hereinafter referred to as "HITACHI"), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefore;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, I/we, the above named, hereby sell, assign, and transfer to HITACHI, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the inventions set forth in said application to HITACHI, its successors and assigns; and we hereby agree that HITACHI may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by HITACHI.

Signed on the date(s) indicated beside my (our) signature(s).

- 1) Signature:  Date: 2/2/09
Typed Name: Hamid Balamane
- 2) Signature: _____ Date: _____
Typed Name: Thomas Dudley Boone, Jr.
- 3) Signature:  Date: 1/22/09
Typed Name: Jordan Asher Katine
- 4) Signature:  Date: 2/3/2009
Typed Name: Barry Cushing Stipe

ASSIGNMENT FOR PATENT APPLICATION

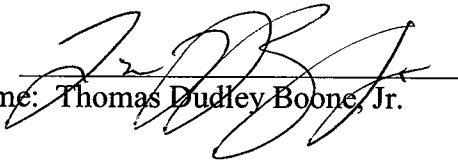
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